

03500.017731

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
HIDEYA KUMOMI ET AL.)	Examiner: Not Yet Assigned
Application No.: Not Yet Assigned)	Group Art Unit: Not Yet Assigned
International Appln. No.: PCT/JP03/15072)	
International Filing Date: November 26, 2003)	
Filed: Herewith)	
For: PRODUCING METHOD FOR CRYSTALLINE THIN FILM)	April 27, 2005

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed Form PTO-1449. Copies of the listed foreign and published technical documents are also enclosed.

The concise explanation of relevance for the non-English documents is found in an attached abstract and, if provided, in a corresponding U.S. Patent. Corresponding U.S. patents and published applications for foreign patent documents in the English language are provided, where available.

10/533091

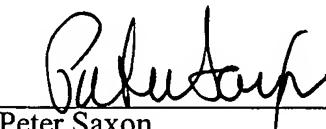
JC12 28 APR 2005

CONCLUSION

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



Peter Saxon
Attorney for Applicants
Registration No.: 24,947

FITZPATRICK, CELLA, HARPER & SCINTO
30 Rockefeller Plaza
New York, New York 10112-3800
Facsimile: (212) 218-2200
497175v1

FORM PTO 1449 (modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)			ATTY DOCKET NO. 03500.017731		APPLICATION NO.: National Stage of PCT/US01/1507 10/533091		
			APPLICANT: HIDEYA KUMOMI				
			FILING DATE Herewith		GROUP NYA		
U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		4,564,403	1/1986	Hayafuji et al.	148	171	
		4,670,088	6/1987	Tsaur et al.	156	617	
		5,021,119	6/1991	Fan et al.			
		5,318,661	6/1994	Kumomi et al.			
		5,453,153	9/1995	Fan et al.			
		5,496,768	3/1996	Kudo, T.	437	174	
		6,326,286	12/2001	Park et al.			
		2003/003766	1/2003	Kumomi et al.			
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
	GB	2338342	12/199	United Kingdom			Corresp to USP 6,326,286
	EP	0472970	3/1992	Europe			Corresp to USP 5,318,661
	EP	1262578	12/2002	Europe			Corresp. to 2003/003766
	WO	89/04550	5/1989	PCT			Corresp. to UPS 5,021,119 and 5,453,153
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
		Kuriyama et al., "Comprehensive Study ... Thin Film Transistors", Jpn. J. Appl. Phys., Vol. 33, (Part 1, No. 10) (1994) 5657-5662.					
		Van Der Wilt, "Grain Location ... Thin Silicon Film", Phys. Stat. Solidi Vol. 166 No. 2, 619-626 (April 1998).					
		Kumomi et al., "Manipulation of nucleation sites ... Si Crystallization", Appl. Phys. Letts., Vol. 59, No. 27, 3565-3567 (Dec. 1999).					
		Hatano et al.; "In situ and ex situ ... laser annealing", J. Non-Cryst. Solids, Vol. 266-269, 654-658 (May 2000)					
		Patent Abstracts of Japan, Vol. 0080, No. 52 (C-213) 3-1984 for JP 58-208297					
		Patent Abstracts of Japan, Vol. 0172, No. 53 (E-1367) 5-1993 for JP04-373171					
		Patent Abstracts of Japan, Vol. 0164, No. 99 (E-1290) 10-1992 for JP04-184918					
EXAMINER			DATE CONSIDERED				